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Further Application for:

Qing Ma et al.

Application No.: 09/883,036

Filed: June 11, 2001

For: APPARATUS FOR ADJUSTING THE
RESONANCE FREQUENCY OF A
MICROELECTROMECHANICAL (MEMS)
RESONATOR USING TENSILE/COMPRESSIVE
STRAIN AND APPLICATIONS THEREFOR

Examiner: Addison, Karen B.

Art Group: 2834

Mail Stop: Issue Fee (Drawings)
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

TRANSMITTAL OF CORRECTED FORMAL DRAWINGS

Dear Sir/Madam:

Enclosed herewith for filing in the above-identified U.S. patent application are the corrected formal drawings, Figures 1-22 (22 sheets).

Respectfully submitted,

BLAKELY SOKOLOFF TAYLOR & ZAFMAN, LLP

Date: 4-20-04

Todd M. Becker
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Certificate of Mailing: I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage in an envelope addressed to Mail Stop: Issue Fee (Drawings), Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450

on April 20, 2004
Date of Deposit

Yuko Tanaka

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Signature

April 20, 2004
Date